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Complete set of claims

- 1. (Previously Amended) A negative aqueous photoresist composition, comprising:
- a) a polymer comprising at least one unit with structure (1)

where R_1 is hydrogen or (C_1-C_4) alkyl and n = 1-4;

- b) a water-soluble photoactive compound;
- c) a crosslinking agent; and,
- d) a solvent composition, and further where the photoactive compound has structure (2),

$$(R_2)_{m}$$
 OCH₃ (2)

where,

 R_2 is hydrogen, alkyl, -O(alkyl), -(alkyl)OH, hydroxyphenyl or multihydroxyphenyl, R_3 and R_4 are independently (C₁-C₄) alkyl, m = 1-3, and,

X is an anion.

- 2. (Delete)
- 3. (Original) The photoresist composition according to claim 1, where solvent composition is water or a mixture of water and a (C_1-C_4) alkyl alcohol.

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- 4. (Original) The photoresist composition according to claim 1, where the polymer contains additional nonaromatic units.
- 5. (Original) The photoresist composition according to claim 4, where the nonaromatic units are selected from a group consisting of ethylenic alcohol, ethylenic pyrollidone, ethylenic acetate, and methylene alcohol.
- 6. (Original) The photoresist composition according to claim 1, where the polymer contains at least 10 mole% of the unit of structure 1.
- 7. (Original) The photoresist composition according to claim 1, where n = 1 and R_1 is selected from methyl, ethyl, propyl and butyl.
- 8. (Previously Amended) The photoresist composition according to claim 2 1, where the photoactive compound is (4-methoxyphenyl)dimethylsufonium trifluoromethanesulfonate.
- (Original) The photoresist composition according to claim 1, where the crosslinker is selected from melamine resins, urea resins and glycolurils.
- 10. (Original) The photoresist composition according to claim 3, where the alcohol is isopropanol.
- 11 (Currently amended) A process for imaging a negative photoresist comprising the steps of:

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- a) forming on a substrate a negative aqueous photoresist composition of claim 1, comprising:
 - i) a polymer comprising at least one unit with structure (1)

where R_1 is hydrogen or (C_1-C_4) alkyl and n = 1-4;

- ii) a water-soluble photoactive compound:
- iii) a crosslinking agent; and,
- iv) a solvent composition;
- b) image-wise exposing the photoresist coating <u>where the image-wise</u> exposure wavelength is below 260nm:
- c) postexposure baking the photoresist coating; and
- d) developing the photoresist coating with a developer.
- 12. (Deleted)
- 13. (Original) The process according to claim 11, where the developer is selected from water, a mixture of water and a (C₁-C₄) alkyl alcohol, mixture of water and surfactant, and an aqueous base solution.
- 14. (Original) The process according to claim 13, where the alcohol is isopropanol.